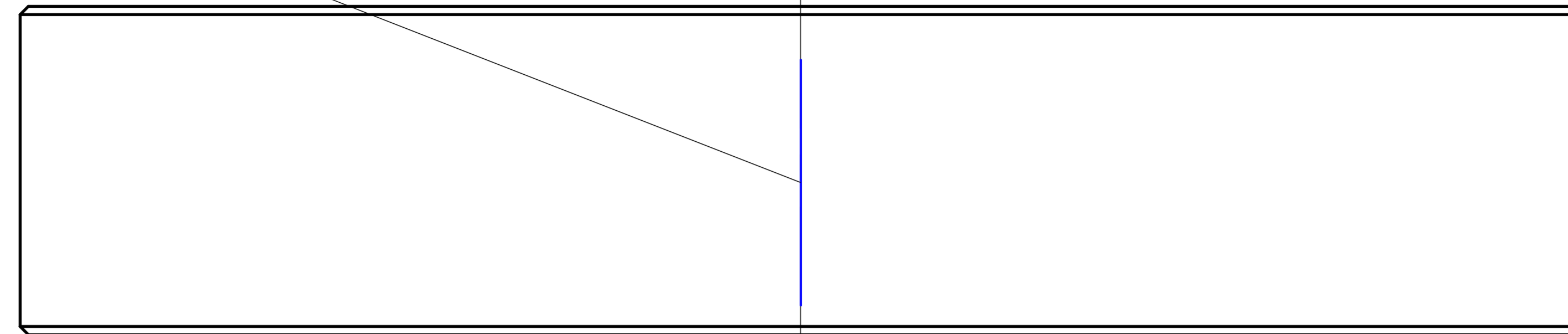
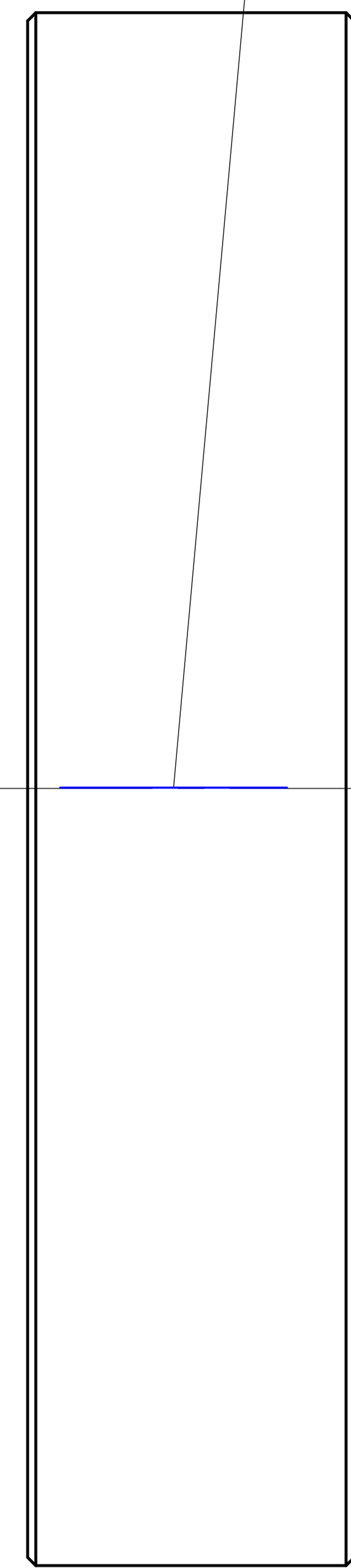


ETCH OR GRIND REGISTRATION MARKS IN THE SAME WAY AS THE MINIMUM THICKNESS LOCATION 90 DEG AWAY.

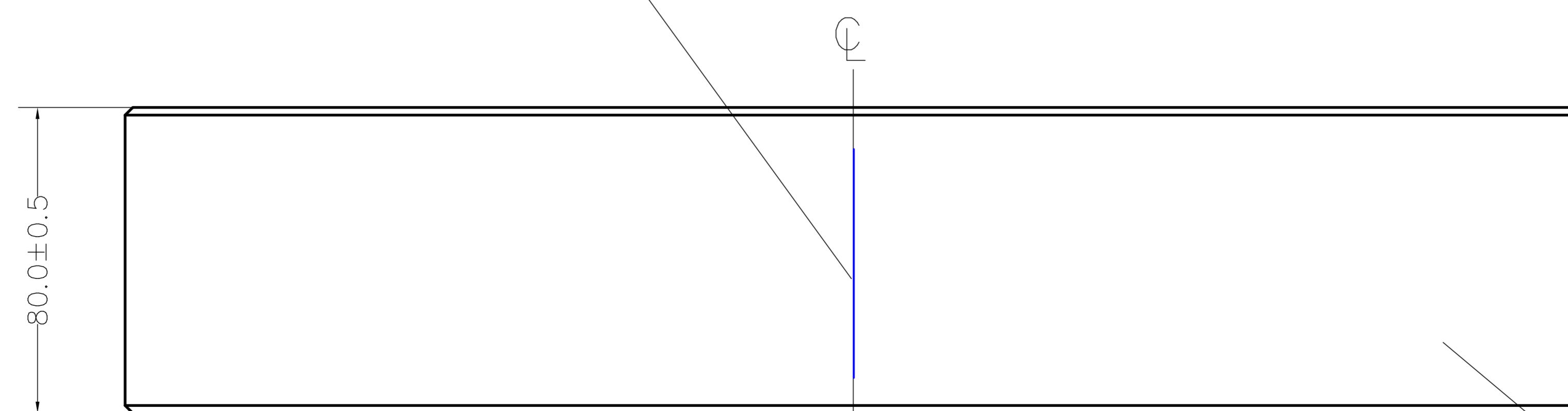


TOP VIEW

ETCH OR GRIND REGISTRATION MARKS IN THE SAME WAY AS THE MINIMUM THICKNESS LOCATION 180 DEG AWAY.



ETCH OR GRIND REGISTRATION MARKS IN THE SAME WAY AS THE MINIMUM THICKNESS LOCATION 90 DEG AWAY.



BOTTOM VIEW

$\phi 380.00 \pm 0.25$

$\square 0.1$
 $\perp 0.1 B$

$0.383^\circ \pm 0.008^\circ$
WEDGE ANGLE

BARREL SIDE AND BEVEL POLISH (SEE NOTE 3)

POLISH SURFACE 'S1' (SEE NOTE 4)

S1

S3

POLISH SURFACE 'S2' (SEE NOTE 4)

S2

(90°)

ETCH OR GRIND SERIAL NUMBER APPROX. WHERE SHOWN LETTERING APPROX. 4mm HIGH. SEE NOTE 5 FOR MORE DETAILS.

ETCH OR GRIND REGISTRATION MARKS $0.25\text{mm} \pm 0.05\text{mm}$ WIDE x $50\text{mm} \pm 3\text{mm}$ LONG MINIMUM LEGIBLE DEPTH LINE ALONG CENTER LINE, CENTERED BETWEEN SURFACES 'S1' AND 'S2' AT LOCATION OF MINIMUM PART THICKNESS WITHIN $\pm 5\text{deg}$ CLOCKING ANGLE (W.R.T. DATUM A), AND PARALLEL TO THE CYLYNDRICAL AXIS (DEFINED BY DATUM A) WITHIN $\pm 0.1\text{mm}$ WITH ARROW POINTING TO SURFACE 'S1'.

NOTES

- DO NOT SCALE FROM THE DRAWING.
- INTERPRET DRAWING AS PER ANSI Y14.5M 1994.
- BARREL SIDE AND BEVEL POLISH PER DOC. PROVIDED.
- FINISH SURFACES 'S1' AND 'S2' AS PER DOC PROVIDED.
- REFER TO DOC. PROVIDED FOR SERIAL NUMBER.
- COATING INFORMATION IS TO BE DETERMINED.
- DIMENSIONS ARE IN MILLIMETERS (mm)

INSTITUTE FOR COSMIC RAY RESEARCH UNIVERSITY OF TOKYO	
SYSTEM: LCGT	
SUB-SYSTEM: MIRROR	
MATERIAL: FUSED SILICA	PART NAME: BEAM SPLITTER SUBSTRATE
DRAWN: E. HIROSE NOV 23, 2011	DWG NO.: MIR-D00003 REV: v1
PAPER SIZE: A0	SCALE: 1:1
PROJECTION:	SHEET: 1/1